

LIST OF PUBLICATIONS

- (1) Resistance changes in thin metallic films under ion implantation.
S.B.Ogale, S.U.Chaisas, A.S.Ogale, V.N.Bhoraskar, A.S.Nigavekar, M.R.Bhiday.
Pramana (India), Vol.15, No.1, P 75-83, July, 1980.
- (2) Some electrical measurements on ion implanted thin metallic and insulating films.
S.V.Chaisas, S.B.Ogale, A.S.Ogale, V.N.Bhoraskar, A.S.Nigavekar, M.R.Bhiday.
Accepted in Radiation Effects (USA) 1982.
- (3) TSC Studies in N_2^+ ion implanted FEP
J.P.Jog, S.B.Ogale, A.S.Ogale, V.N.Bhoraskar, M.R.Bhiday.
Pramana 14 (3), 343-348, 1980. ●
- (4) 200 KeV Ion Implantation System
S.B.Ogale, A.S.Ogale, V.N.Bhoraskar, M.R.Bhiday, N.P. & S.S.P. Symposium of DAE 1978.
- (5) Resistance changes in N_2^+ , C^+ , Ar^+ implanted Cu, Al, & Bi films.
S.B.Ogale, A.S.Ogale, V.N.Bhoraskar, M.R.Bhiday
Dept. of Atomic Energy, Nuclear Physics and Solidstate Physics Symposium, 1979.
- (6) 200 KeV Ion Implantation System
S.B.Ogale, A.S.Ogale, V.N.Bhoraskar, M.R.Bhiday
Technical Report, Department of Physics,
University of Poona.